MRS Members Elect 1992 Officers, Councillors

In the yearly elections held this past September, MRS members elected eight colleagues to leadership positions in the MRS Council. Newly elected as MRS officers are First Vice President and President Elect, S. Thomas Picraux, Second Vice President John C. Bravman, and Secretary Lynn A. Boatner. The six newly elected Councillors include Aaron N. Bloch, R.P.H. Chang, Russell R. Chianelli, Robert Hull, Carol M. Jantzen, and Paul S. Peercy.

Previously elected First Vice President in 1991, G. Slade Cargill automatically becomes the 1992 MRS President. Also in 1992, Charles B. Duke continues as Treasurer in his two-year position, and 1991 President James B. Roberto serves as Immediate Past President.

1992 MRS Officers

President G. Slade Cargill III (1992) IBM T.J. Watson Research Center Immediate Past President James B. Roberto (1992) Oak Ridge National Laboratory First Vice President (President Elect)

* S. Thomas Picraux (1992) Sandia National Laboratories

Second Vice President

* John C. Bravman (1992) Stanford University

Secretary

* Lynn A. Boatner (1993) Oak Ridge National Laboratory

Treasurer

Charles B. Duke (1992) Xerox Webster Research Center

1992 MRS Councillors

John E.E. Baglin (1992) IBM Almaden Research Center

- * Aaron N. Bloch (1994) Columbia University
- * R.P.H. Chang (1994) Northwestern University
- * Russell R. Chianelli (1994) Exxon Research and Engineering Company

Mildred S. Dresselhaus (1992) Massachusetts Institute of Technology Gregory C. Farrington (1993) University of Pennsylvania

J. Murray Gibson (1992) University of Illinois-Urbana

- * Robert Hull (1994) AT&T Bell Laboratories
- * Carol M. Jantzen (1994)
 Westinghouse Savannah River
 Company

Edward J. Kramer (1992) Cornell University

* Paul S. Peercy (1994) Sandia National Laboratories

Julia M. Phillips (1993) AT&T Bell Laboratories

Rustum Roy (1993) Pennsylvania State University

Frans Spaepen (1992) Harvard University

Carl V. Thompson (1993)
Massachusetts Institute of Tock

Massachusetts Institute of Technology

* Newly Elected

* Newly Elected .

(Term of office expines at end of year indicated in parenthesis.)

MRS Establishes David Turnbull Lectureship

The Materials Research Society recently approved establishment of the David Turnbull Lectureship. This yearly award will recognize the career of a scientist who has made outstanding contributions to understanding materials phenomena and properties through research, writing, and lecturing, as exemplified by the life work of David Turnbull. The Lectureship will also be a means to provide lectures of exceptional quality and scientific significance for the MRS Fall Meeting as well as, possibly, MRS Section and University Chapter meetings.

The Turnbull Lecturer will receive a \$2,000 honorarium and a citation plaque. The award will include travel expenses to the MRS meeting at which the Turnbull Lecture is given and also additional funds to enable the recipient to speak as the Turnbull Lecturer for MRS Sections and University Chapters.

Plans are to name the first David Turnbull Lecturer at the 1992 MRS Fall Meeting and nominations are being accepted.

Rules and Eligibility

Nominations for the Turnbull Lecturer may be made for scientists and engineers

in all areas of materials science. The primary consideration in making the award is the nominee's career contribution to the fundamental understanding of materials phenomena and properties, through research, writing, and lecturing.

Nominees need not be members of the Materials Research Society, and nominees of any national origin or citizenship are eligible.

Current members of the MRS Awards Committee, MRS officers, and previous Turnbull Lecturers are not elibible.

Selection of the Turnbull Lecturer must be approved by the MRS Executive Committee with recommendation from the Awards Committee. The decision of the Executive Committee is final.

The Lectureship will not be awarded in absentia. The Lecture must be given within 12 months of the selection at an MRS Fall Meeting.

Nomination Procedure

A package containing the following is required:

1. A statement by the nominator supporting the candidate's suitability to be designated the Turnbull Lecturer, with respect to the importance of the candidate's research contributions to the fundamental understanding of materials, quality of the candidate's writing and lectures, candidate's role in education and graduate training in materials research.

2. Supporting information and documents, e.g., curriculum vitae including a list of key publications.

- 3. Letters of support from established scientists familiar with the nominee's qualifications and area of research. Only three such letters will be accepted with each nomination. Each letter should make specific reference to the criteria listed in item 1.
- 4. A list of supporting documents submitted. The entire nomination package, excluding (p)reprints, should not exceed 12 pages.

A nomination for a Turnbull Lectureship remains under consideration for three years, and it may be updated by the nominator during that time.

Nominations can be submitted to: John B. Ballance, Executive Director, Attention: Turnbull Lectureship (B), Materials Research Society, 9800 McKnight Road, Pittsburgh, PA 15237.

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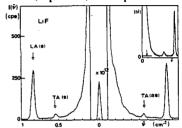
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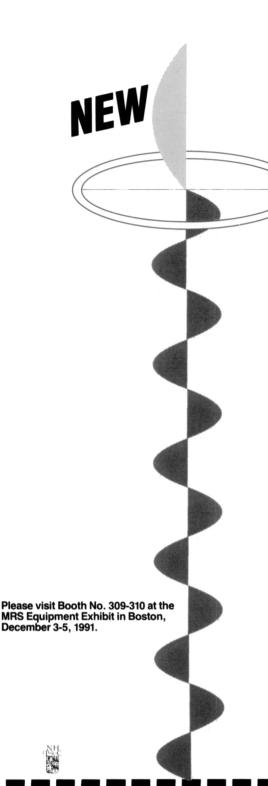
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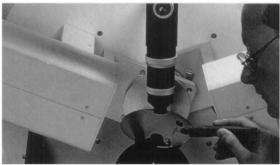
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